

In re application of

Confirmation No. 6344

Yoshio YANASE et al.

Docket No. 2001-0615A

Serial No. 09/856,982

[Group Art Unit 2877

Filed May 30, 2001

Examiner Sang H. Nguyen]

METHOD FOR INSPECTING SEMICONDUCTOR WAFER SURFACE

Approved by examinar (05/17/03)

SUBMISSION OF FORMAL DRAWINGS

Assistant Commissioner for Patents, Washington, DC 20231

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT ACCOUNT NO. 23-0975

Sir:

One sheet of formal (A4P) drawings (Figs. 12 and 13) are submitted herewith.

Respectfully submitted,

Yoshio YANASE et al.

By:

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March 13, 2003

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